

PATENT 1691-0170P

## IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant:

Satoru WAKAMATSU et al. Conf.:

4641

Appl. No.:

10/030,657

Group:

Filed:

January 11, 2002

THE CHILLIANS OF THE PROPERTY Examiner: Hoa Le

For:

POLYCRYSTALLINE SILICON, METHOD AND

APPARATUS FOR PRODUCING THE SAME

## LARGE ENTITY TRANSMITTAL FORM

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450 December 23, 2003

#### Sir:

Transmitted herewith is an amendment in the above-identified application.

The enclose	ed document	is being	transmitted	via	the	Certificate
of Mailing	provisions	of 37 C	.F.R. § 1.8.			

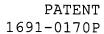
The enclosed document is being transmitted via facsimile.

The fee has been calculated as shown below:

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NUMBER PREVIOUSLY PAID FOR		PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	16	_	20	=	0	\$ 18	\$0.00
INDEPENDENT	3	_	3	=	0	\$ 86	\$0.00
FIRST PRESENTATION OF A MULTIPLE DEPENDENT CLAIM					\$290	\$0.00	
· · · · · · · · · · · · · · · · · · ·						TOTAL	\$0.00

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		nonth(s) extension of time pursuant $(1.136(a))$ . $(3.00)$ for the extension of							
$\boxtimes$	No fee is required.								
	Check(s) in the amount of \$0.00 is(are) enclosed.								
	Please charge Deposit A \$0.00. This form is sub	Account No. $02-2448$ in the amount omitted in triplicate.	οf						
If necessary, the Commissioner is hereby authorized in this concurrent, and future replies, to charge payment or credit an overpayment to Deposit Account No. 02-2448 for any additional fee required under 37 C.F.R. § 1.16 or under 37 C.F.R. § 1.17 particularly, extension of time fees.									
Respectfully submitted,									
		BIRCH, STEWART, KOLASCH & BIRCH, LI	ιP						
		By Marc S. Weiner, #32,181							
MSW/: 1691	jmb -0170P	P.O. Box 747 Falls Church, VA 22040-0747 (703) 205-8000							
Atta	chment(s)	(Rev. 09/30/	03)						





### IN THE U.S. PATENT AND TRADEMARK OFFICE

Applicant: Satoru WAKAMATSU et al. Conf.: 4641

Appl. No.: 10/030,657 Group: 1773

Filed: January 11, 2002 Examiner: Hoa Le

For: POLYCRYSTALLINE SILICON, METHOD AND

APPARATUS FOR PRODUCING THE SAME

# REPLY UNDER 37 C.F.R. § 1.111

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

December 23, 2003

#### Sir:

In reply to the Office Action dated October 1, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

This reply includes amendments to the specification, amendments to the claims and Remarks.